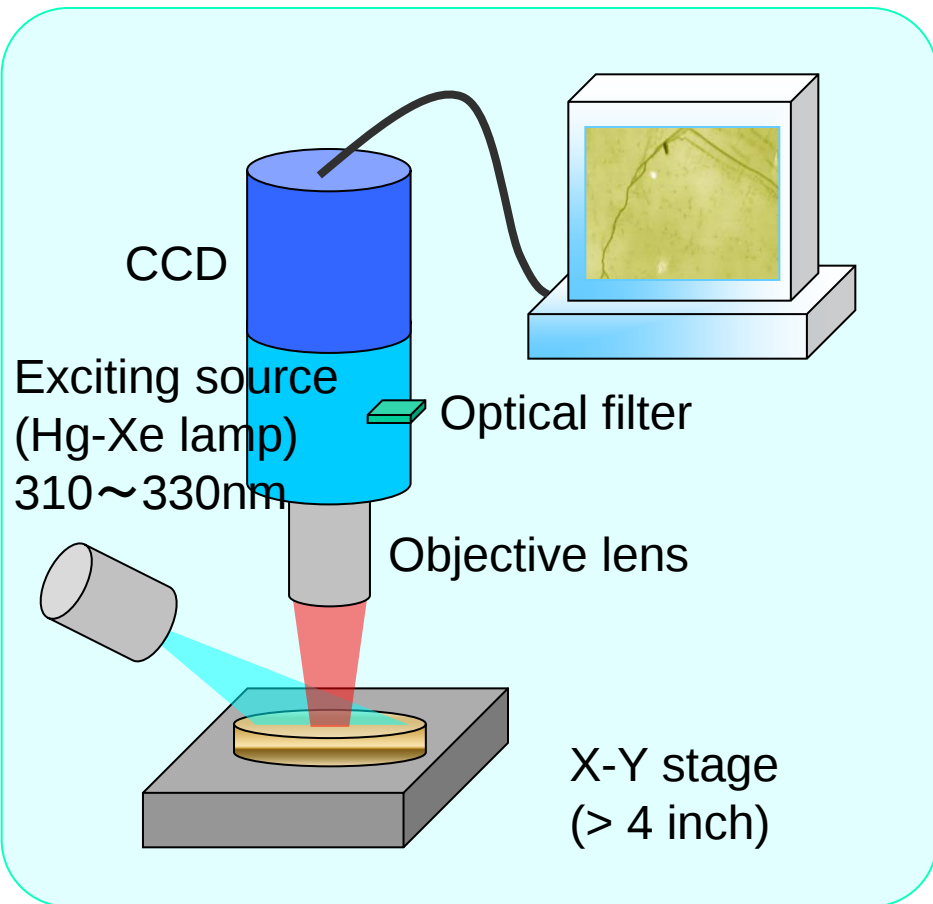
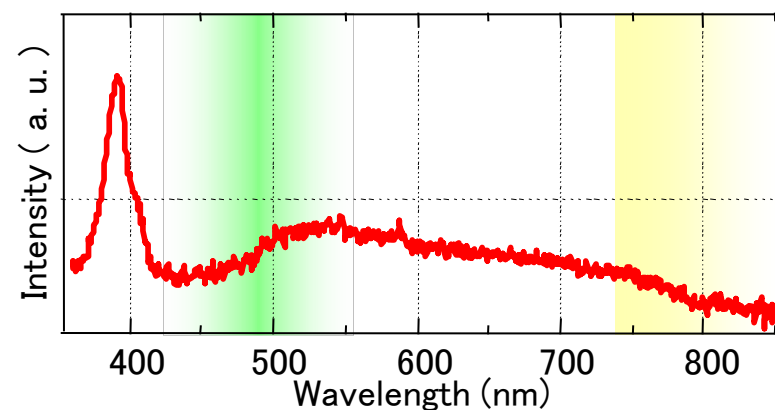
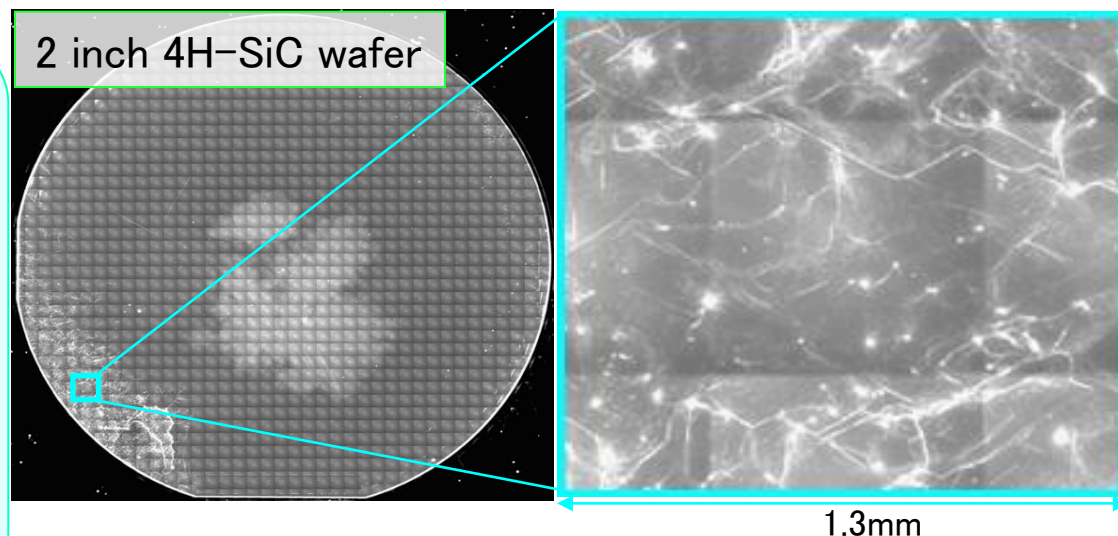


Defect evaluation by PL imaging

Example 4H-SiC wafer



Schematic diagram of PL-imaging method



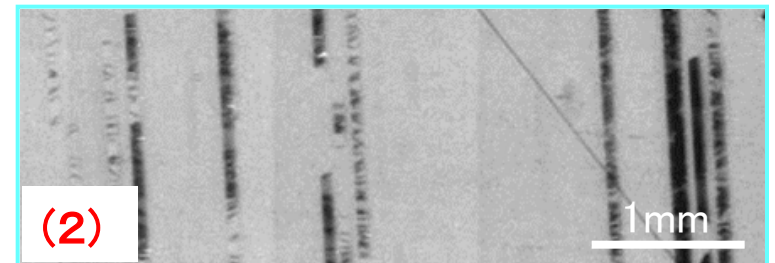
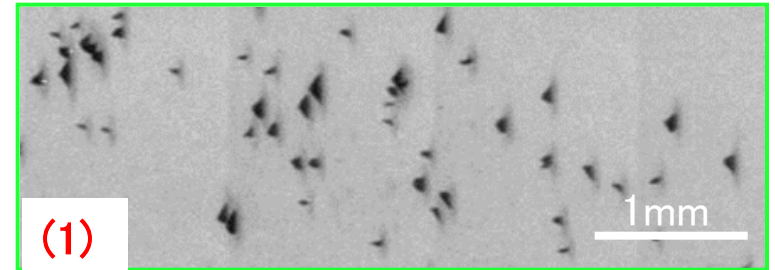
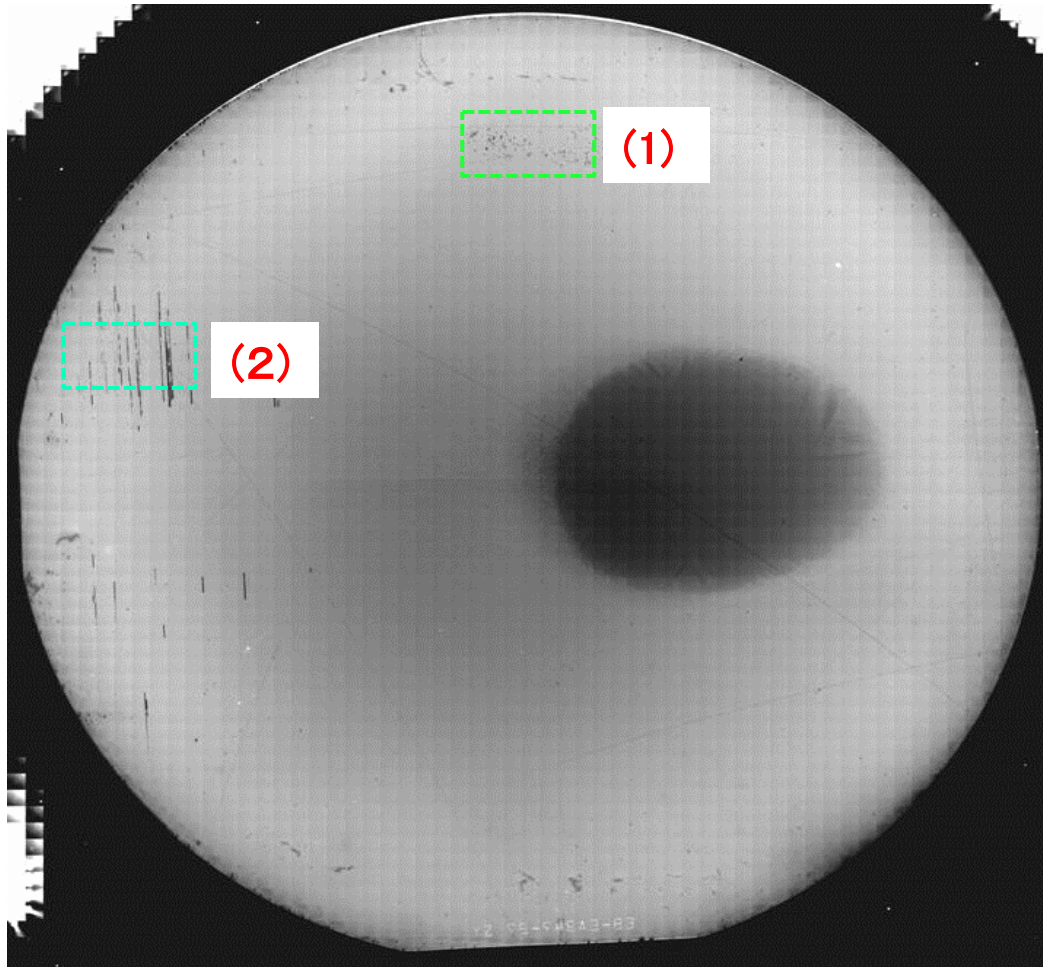
PL spectrum in 4H-SiC



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PL image of 3-inch 4H-SiC wafer

Sample: 4H-SiC (3 inch)



PL image ($\lambda > 325\text{nm}$)



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